



86397

PATENT

AF/1763  
Bfw

## THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re U.S. Patent Application

) Examiner: Robert M. Kunemund

Applicants: Satoshi Komiya et al.

) Art Unit: 1765

Serial No.: 10/049,875

) Confirmation No.: 2326

Filed: February 12, 2002

) I hereby certify that this correspondence is being  
) deposited with the United Postal Service as first  
) class mail in an envelope addressed to: MAIL  
) STOP AMENDMENT, Commissioner for  
) Patents, P.O. Box 1450, Alexandria, Virginia  
) 22313-1450, dated June 2, 2004For: **SILICON WAFER AND  
METHOD FOR  
MANUFACTURE THEREOF,  
AND METHOD OF  
EVALUATION OF SILICON  
WAFER**)   
) Gerald T. Shekleton Reg. No. 27,466AMENDMENT TRANSMITTALMail Stop AMENDMENT  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

Transmitted herewith is an amendment in the above-identified application.

(X) No additional fee is required.

Fee Calculation For Claims As Amended

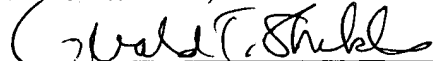
	As Amended		Previously Paid For		Present Extra	Rate	Additional Fee
Total Claims	14	-	20	=	0	x\$18.00=	\$_____
Independent Claims	5	-	5	=	0	x\$86.00=	\$_____
Multiple Dependent Claims						x\$____.00=	\$_____
Total Additional Fee							\$_____

( ) A check in the amount of \$\_\_\_\_\_ is attached.

(x) The Commissioner is hereby authorized to charge any additional fees which may be required to this application number under 37 C.F.R. § 1.16-1.17, or credit any overpayment, to Deposit Account No. 23-0920. Should no proper amount be enclosed herewith, as by a check being in the wrong amount, unsigned, post-dated, otherwise improper or informal or even entirely missing, the Commissioner is authorized to charge the unpaid amount to Deposit Account No. 23-0920.

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Gerald T. Shekleton  
Registration No. 27,466

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**AMENDMENT**

MAIL STOP AMENDMENT

Commissioner for Patents

P.O. Box 1450

Alexandria, Virginia 22313-1450

Sir:

The Office Action of March 9, 2004 has been carefully reviewed and the following amendment and remarks are made in response thereto.